

OK to exec
J. Wilson 5/24/01



CA

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): KATO, et al.

Serial No.: 09/461,432

Filed: December 16, 1999

For: VACUUM PROCESSING APPARATUS AND OPERATING
METHOD THEREFOR

Group: 3749

Examiner: S. Gravini

Allowed: December 7, 2000

Batch No.: W11

Match and Return

FURTHER AMENDMENT UNDER 37 CFR 1.312

Assistant Commissioner for Patents

Box Issue Fee

Washington, D.C. 20231

March 7, 2001

Sir:

Further amending the claims as proposed to be amended in the Amendment Under 37 CFR 1.312 submitted January 18, 2001, and concurrently with payment of the Issue Fee responsive to the Notice of Allowance mailed December 7, 2000, please further amend the above-identified application as follows:

IN THE CLAIMS

Please amend the claims presently in the application as follows:

SUB E1

1. (Twice Amended) A method of using a conveyor system for processing substrates in plural vacuum processing chamber installation portions, the conveyor system including:
an atmospheric loader, having a location for